

Tool ID: 221  
Tool Location: 106

Equipment Information Sheet  
**Harrick Plasma Generator (Clean room)**

**Manager:** Xinwei Wu  
**Backup:** Tom Pennell

607-254-4934  
607-254-4309

Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.

**SAFETY**

- RF energy present

**USAGE RESTRICTIONS**

- Please contact the tool manager BEFORE using substrates *other than* glass, silicon or PDMS.

**SCHEDULING/SIGN-UP RESTRICTIONS**

- None

*Minimum Tool Time: 15 minutes*

**MATERIALS COMPATIBILITY CATEGORY**

**Tool Category 5: Class A and B Metals and Compounds**

<b>Allowed</b>	<b>Not Allowed</b>
Tool category 1/1E, 2, 3, and 4 materials	
Silicon Based Substrates and Films	
III/V compound Semiconductors	
Glass Substrates	
PECVD and ALD Films	
Cured organics and baked Photoresist	
CNF Class A, B, and Refractory metals	
Exposed Gold, Silver, Copper	
Alkali and Alkaline Compounds	
Organic/Biology Molecules prepared-w/salt buffers	
High Vapor Pressure Materials (Mg, Ca, Zn)*	* Some tool restrictions on high vapor pressure materials may apply
Soft organic materials	

**High Vapor Pressure Metals and Compounds** are materials that have a vapor pressure above  $1e-6$  Torr at 400 C.

**Additional Material Restrictions and Exceptions**

- No flammable materials or liquids allowed
- No uncured PDMS allowed.

*Last Updated: 06/10/2021*